

Form PTO-1449
(Rev. 8-83)U.S. Department of Commerce
Patent and Trademark Office

Attorney Docket No. 0756-1984

Serial No. Not Yet Assigned

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

Applicant: Shunpei YAMAZAKI et al.

Filing Date: June 17, 1999

Group: 2811

U.S. PATENT DOCUMENTS

Examiner Initial	Patent Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
	5,581,092	12/03/96	Takemura			
SAL	5,500,538	03/19/96	Yamazaki et al.			
SAL	5,147,826	09/15/92	Liu et al.			
SAL	5,275,851	01/04/94	Fonash et al.			
SAL	5,731,613	03/24/98	Yamazaki	257	350	
SAL	5,581,092	12/03/96	Takemura	257	192 65	

FOREIGN PATENT DOCUMENTS

Document Number	Date	Country	Class	Subclass	Translation Yes No

OTHER DOCUMENTS (Including Author, Title, Relevant Pages, Date, Place of Publication)

	C. Hayzelden et al., "In Situ Transmission Electron Microscopy Studies of Silicide-Mediated Crystallization of Amorphous Silicon" (3 pages)
	A.V. Dvurechenskii et al., "Transport Phenomena in Amorphous Silicon Doped by Ion Implantation of 3d Metals", Akademikian Lavrentev Prospekt 13, 630090 Novosibirsk 90, USSR, pp. 635-640.
SAL	T. Hempel et al., "Needle-Like Crystallization of Ni Doped Amorphous Silicon Thin Films", <u>Solid State Communications</u> , Vol. 85, No. 11, pp. 921-924, 1993.
SAL	R. Kakkad et al., "Crystallized Si films by low-temperature rapid thermal annealing of amorphous silicon," <u>J. Appl. Phys.</u> , 65(5), March 1, 1989, pp. 2069-72.
SAL	G. Liu et al., "Polycrystalline silicon thin film transistors on Corning 7059 glass substrates using short time, low-temperature processing," <u>Appl. Phys. Lett.</u> 62(20), May 17, 1993, pp. 2554-2556.
SAL	G. Liu et al., "Selective area crystallization of amorphous silicon films by low-temperature rapid thermal annealing," <u>Appl. Phys. Lett.</u> 55(7), August 14, 1989, pp. 660-662.
	R. Kakkad et al., "Low Temperature Selective Crystallization of Amorphous Silicon," <u>Journal of Non-Crystalline Solids</u> , 115, 1989, pp. 66-68.

Examiner

Shunpei Yamazaki

Date Considered

12-14-99

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.